## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.

: 10/579,777

Confirmation No.: 5716

First Named Inventor : Hiraku ISHIKAWA

Filed

: February 26, 3008

TC/A.U.

: 1792

Examiner

: Shamim Ahmed

Docket No.

: 101994.57726US

Customer No.

: 23911

Title

: Plasma Film-Forming Apparatus and Plasma Film-

Forming Method

## REPLY TO OFFICE ACTION

## Mail Stop AF

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

The following remarks are respectfully submitted in response to the final Office Action dated April 21, 2009.

The Listing of Claims begins on page 2 of this paper.

Remarks begin on page 5 of this paper.